

Title (en)

Process and apparatus for measuring and controlling the carburising atmosphere in a vacuum carburising installation

Title (de)

Vorrichtung und Verfahren zum Messen und/oder Regeln der Aufkohlungsatmosphäre in einer Vakuumgasaufkohlungsanlage

Title (fr)

Procédé et installation pour mesurer et réguler l'atmosphère de cémentation dans une installation de cémentation sous vide

Publication

EP 1306462 A3 20031029 (DE)

Application

EP 02023737 A 20021023

Priority

DE 10152204 A 20011023

Abstract (en)

[origin: EP1306462A2] Measurement and/or regulation of the carburization atmosphere in a carburization chamber (3) of a vacuum gas carburization system (1) comprises introducing workpieces into the chamber, providing and maintaining a vacuum in the chamber, introducing a carburization gas into the chamber and measuring the atmosphere in the chamber using a probe. <??>An Independent claim is also included for a vacuum gas carburization system comprising at least one carburization chamber having an opening in which a probe for measuring the atmosphere in the chamber is arranged in a vacuum-tight manner. <??>Preferred Features: The probe is a vacuum-tight oxygen sensor used for measuring zirconium oxide ceramic.

IPC 1-7

C23C 8/20; **C23C 8/22**

IPC 8 full level

C23C 8/20 (2006.01); **C23C 8/22** (2006.01)

CPC (source: EP)

C23C 8/20 (2013.01); **C23C 8/22** (2013.01)

Citation (search report)

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